

Fig.1

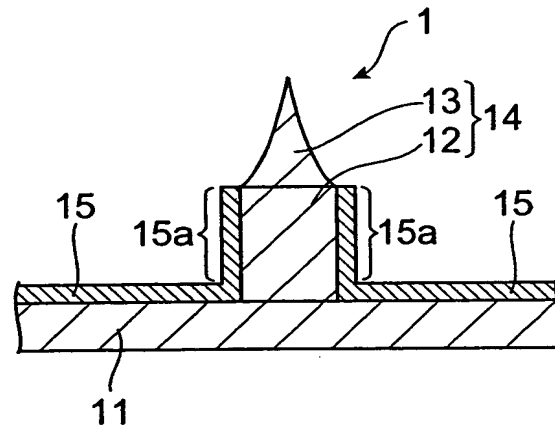


Fig.2

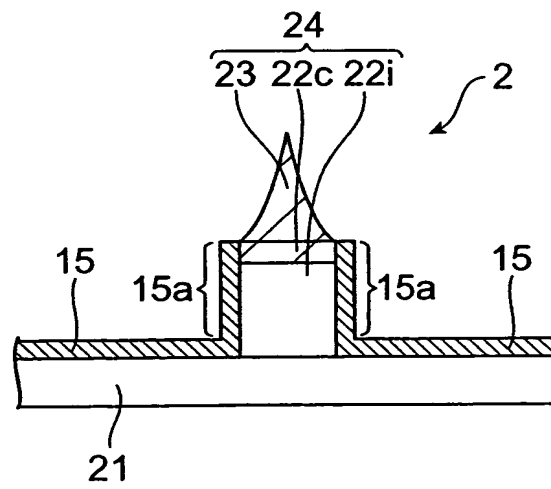


Fig.3

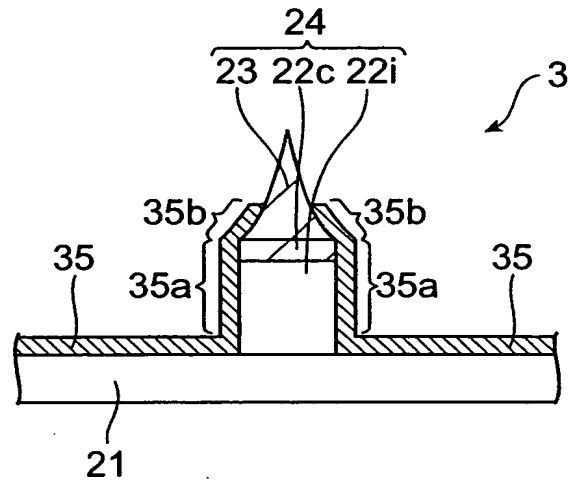


Fig.4

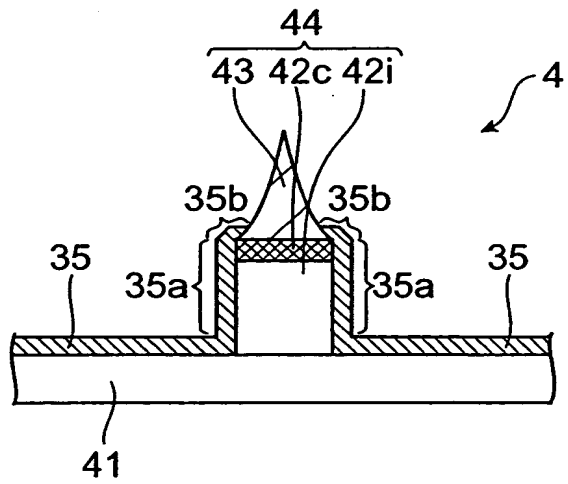


Fig.5

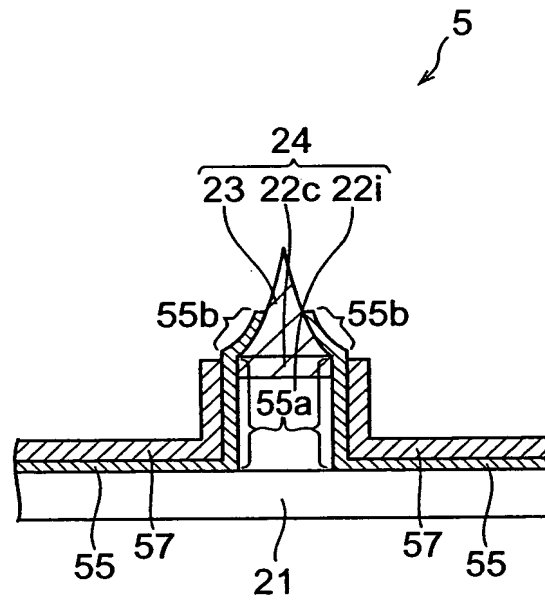


Fig.6A

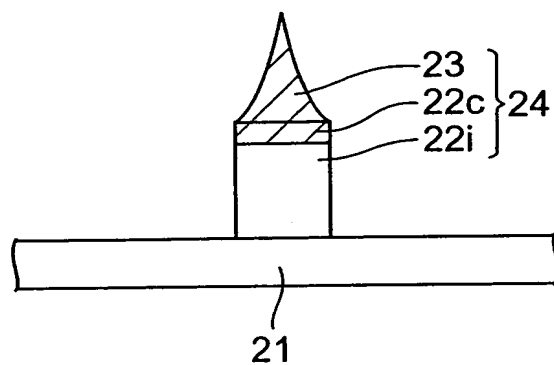


Fig.6B

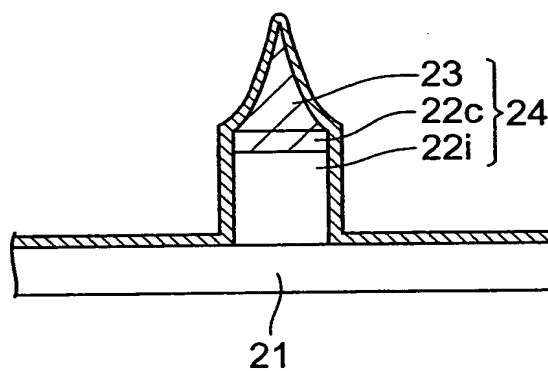
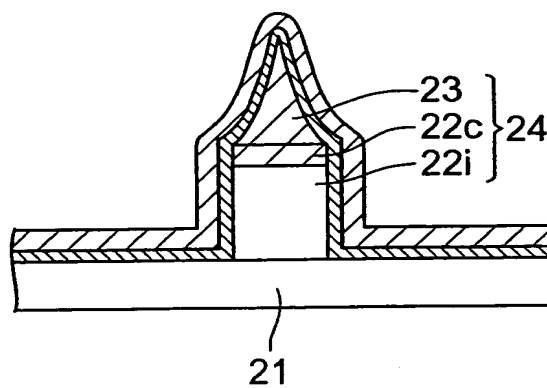


Fig.6C



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Fig.7A

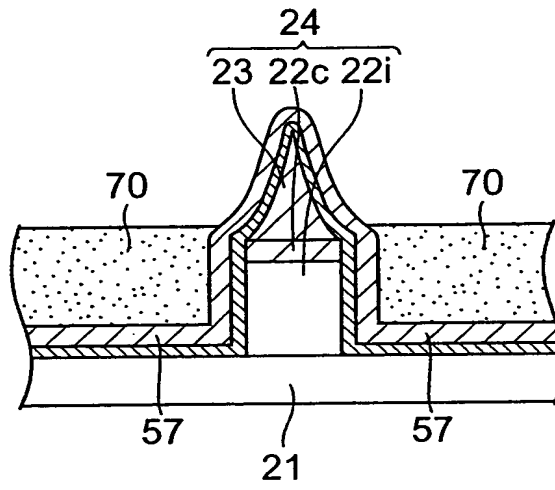


Fig.7B

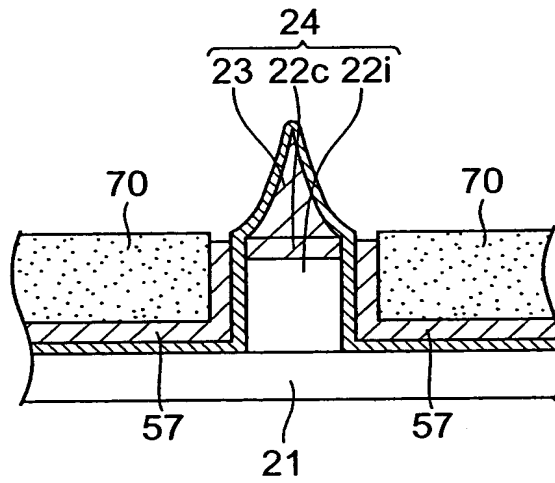
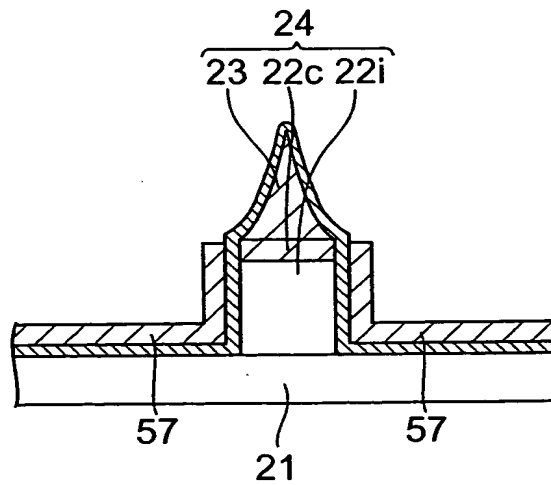


Fig.7C



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Fig.8A

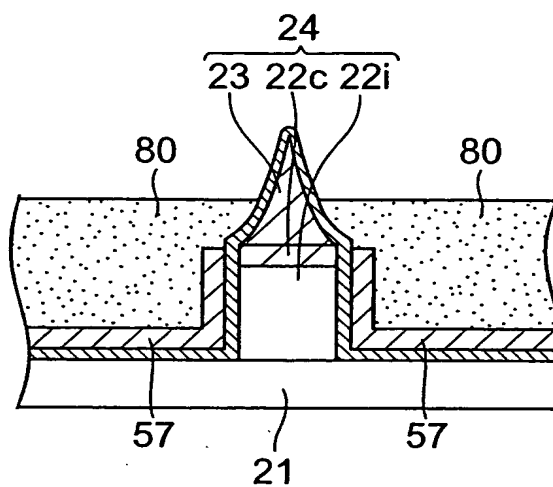


Fig.8B

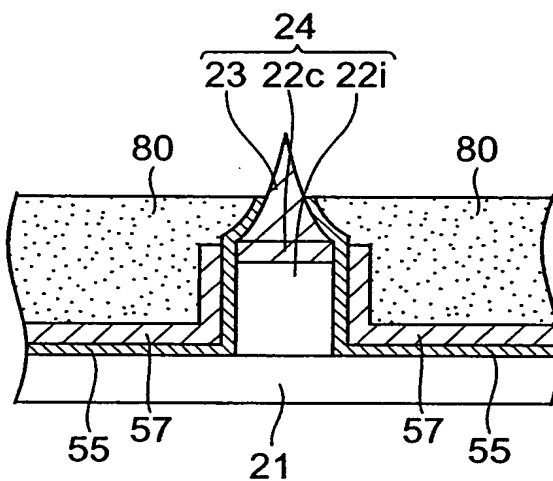
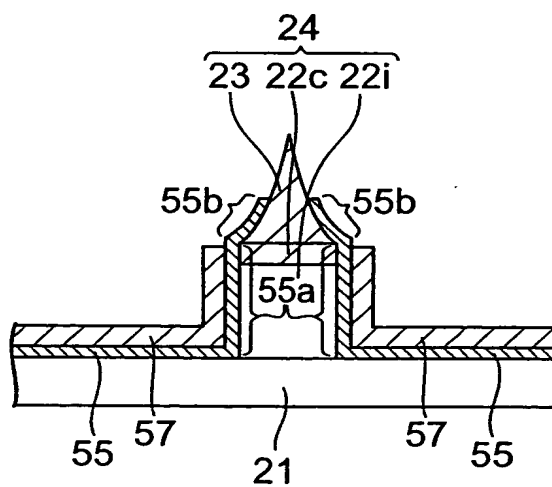


Fig.8C



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Fig.9A

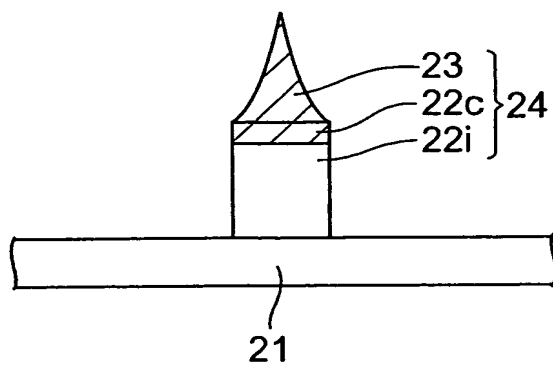


Fig.9B

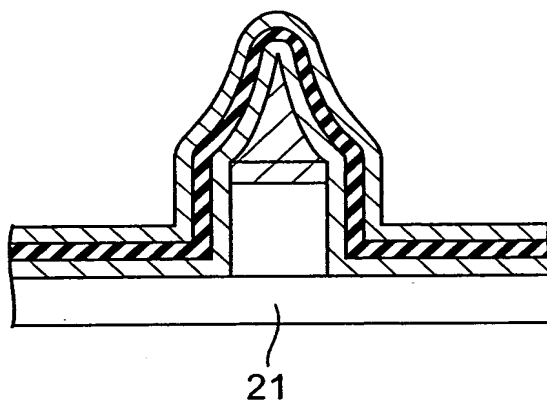


Fig.9C

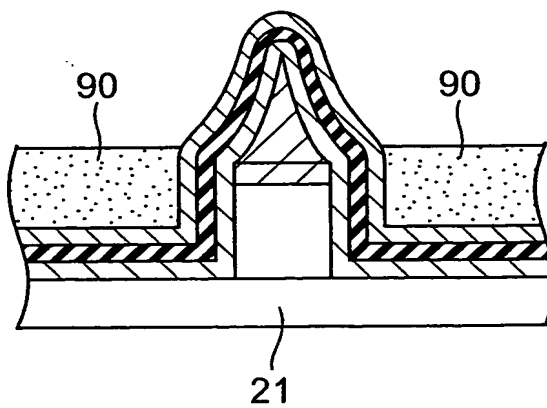


Fig.10A

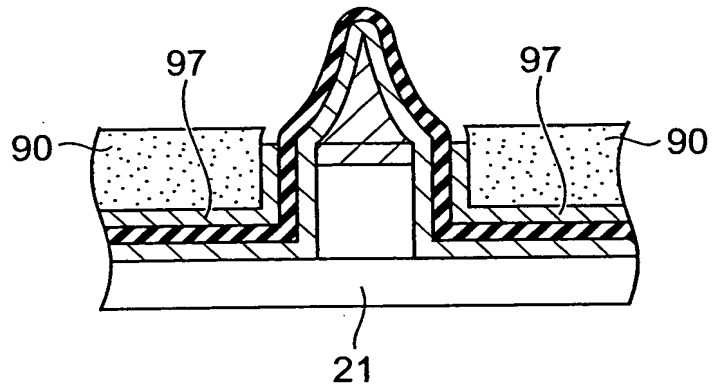


Fig.10B

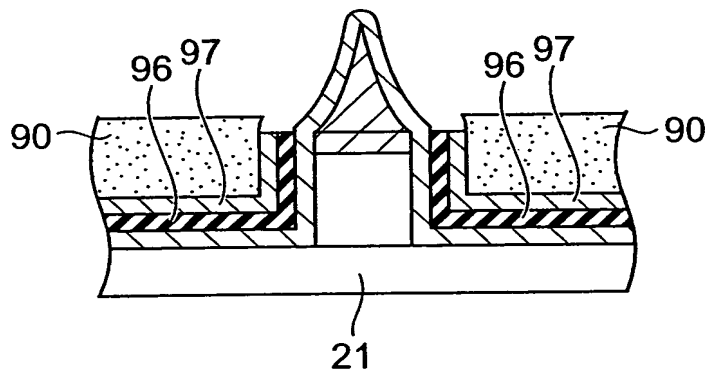


Fig.10C

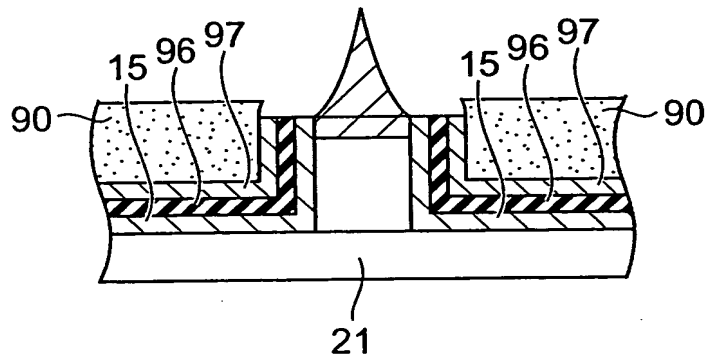
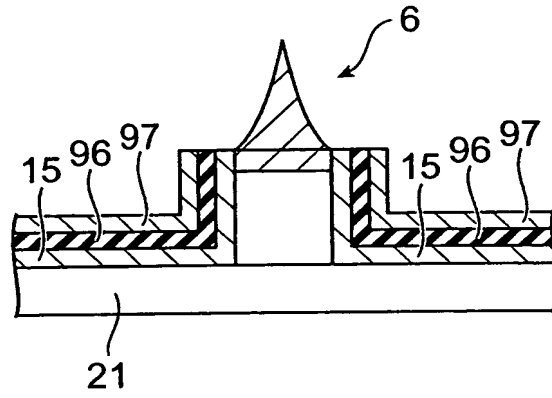


Fig.11



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Fig.12

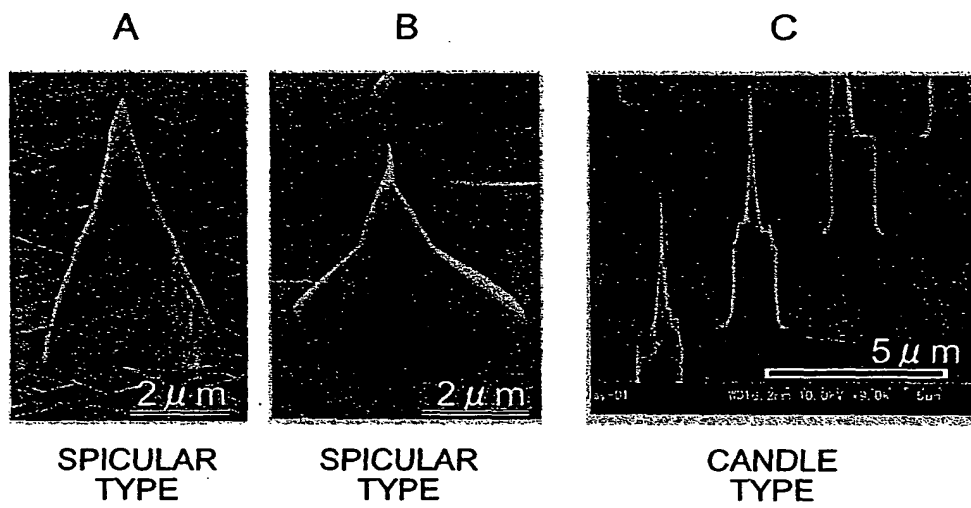


Fig.13

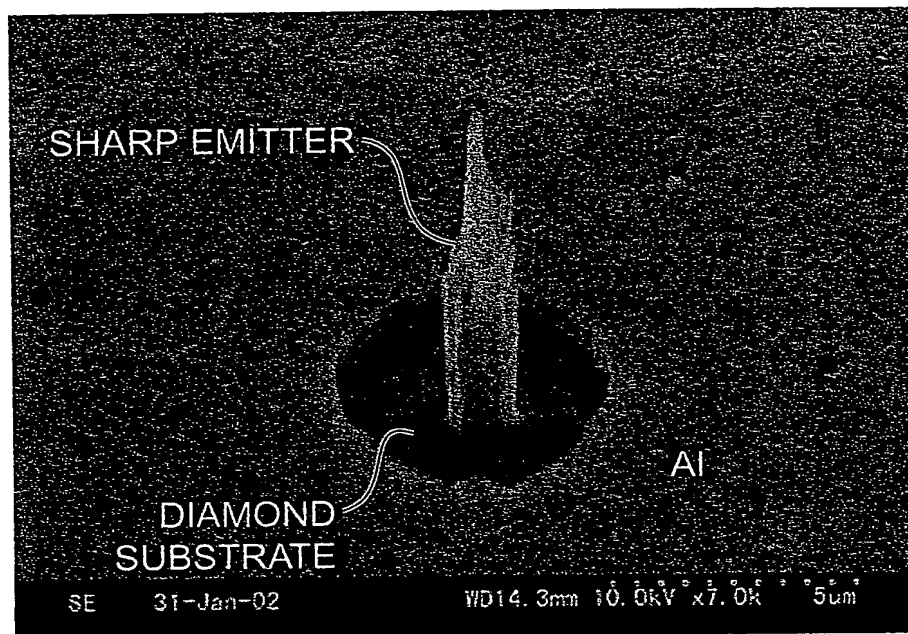
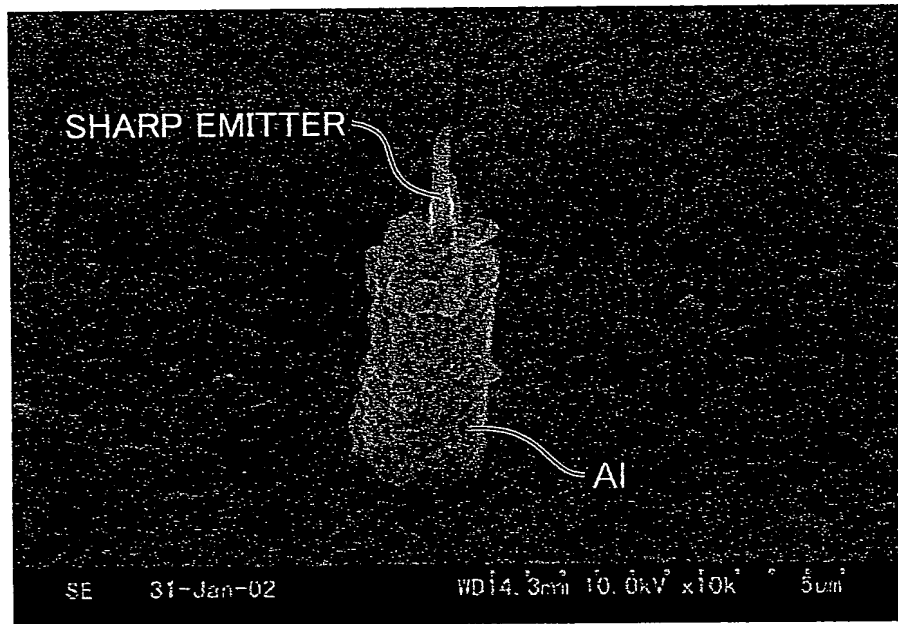
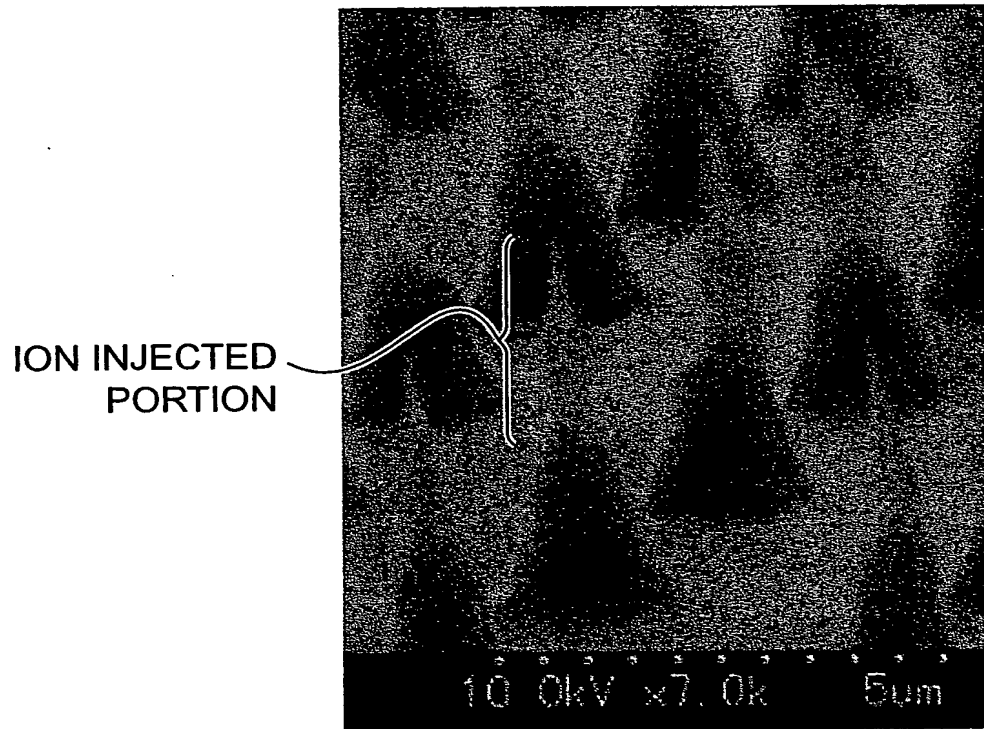


Fig.14



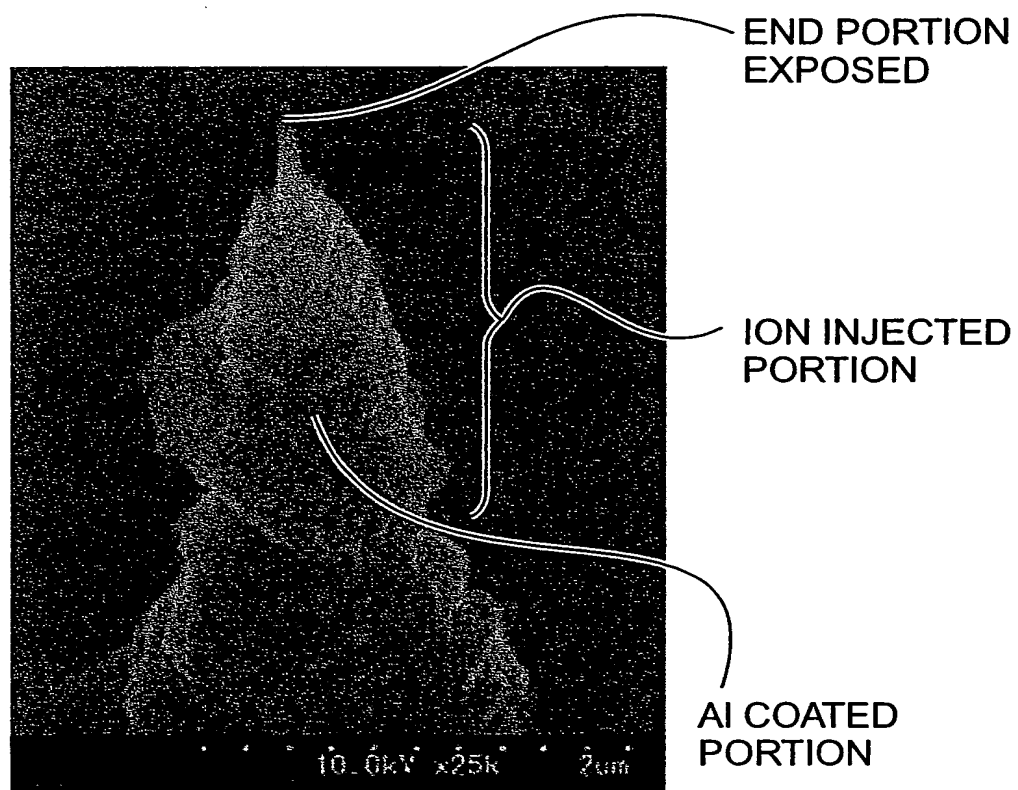
SHARP EMITTER WITH AN AL ELECTRODE

Fig.15



SHARP EMITTER
WITH AN Al ION INJECTED LAYER

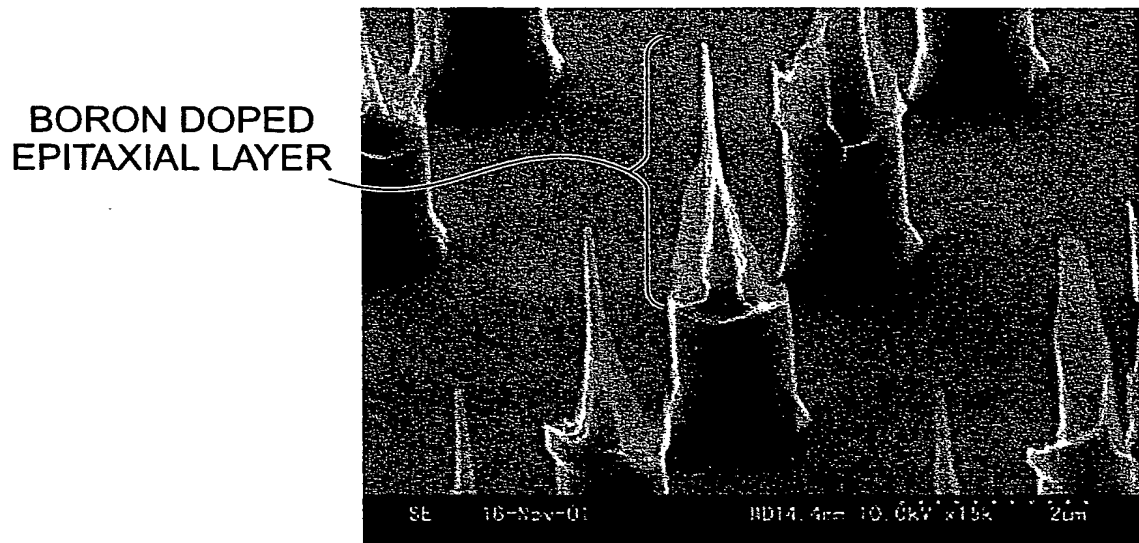
Fig.16



PROTRUSION WHERE AN AI ELECTRODE
IS FORMED EXCEPT FOR THE TIP

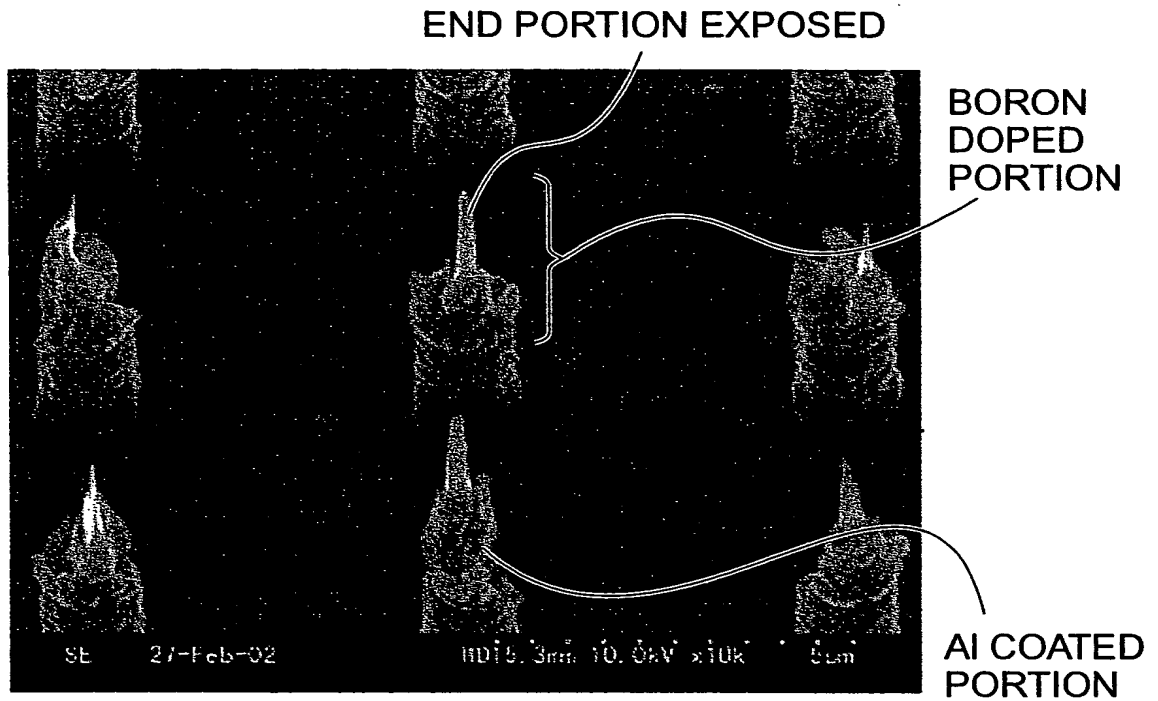
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Fig.17

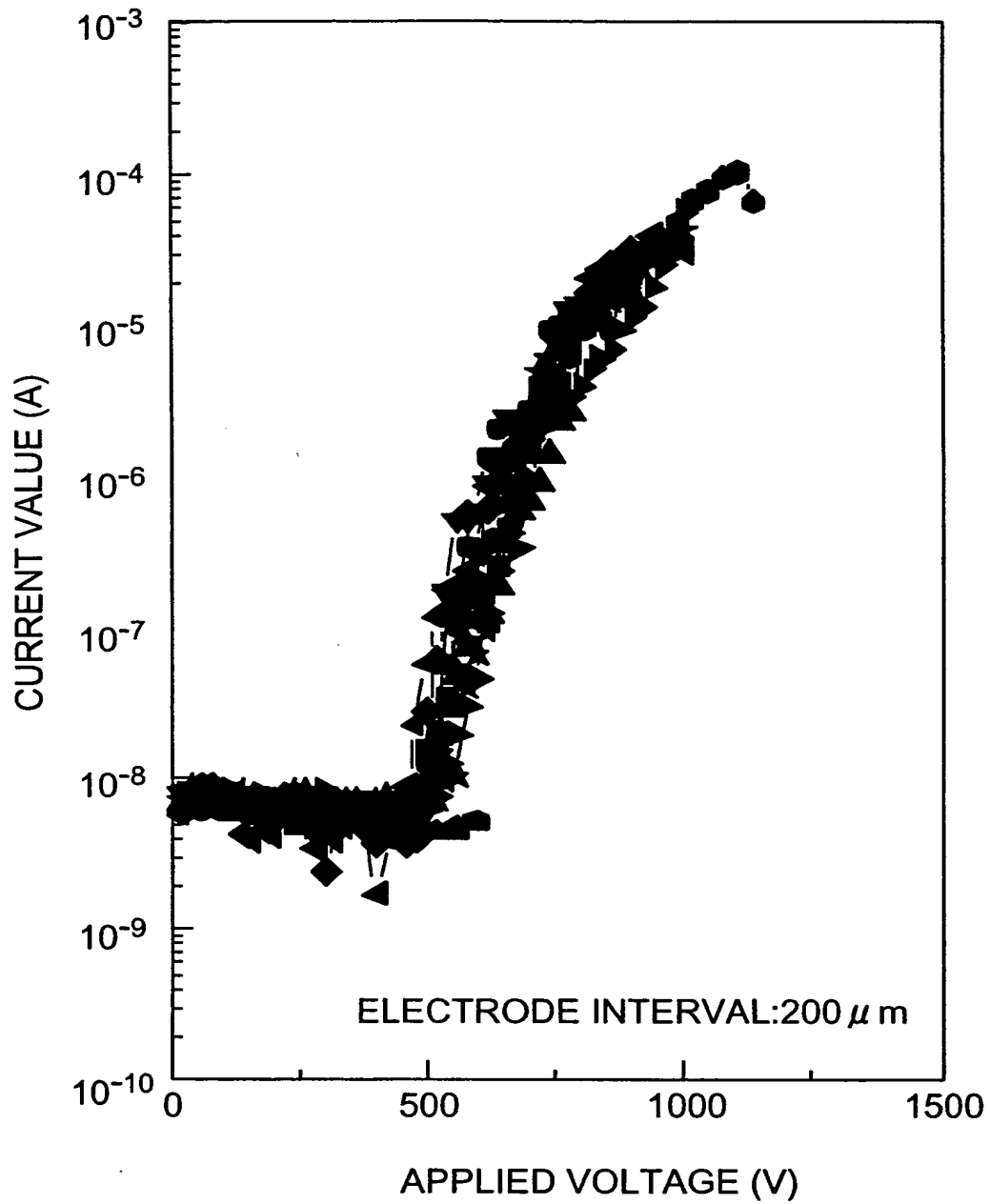


SHARP EMITTER INCLUDING
A BORON DOPED EPITAXIAL LAYER

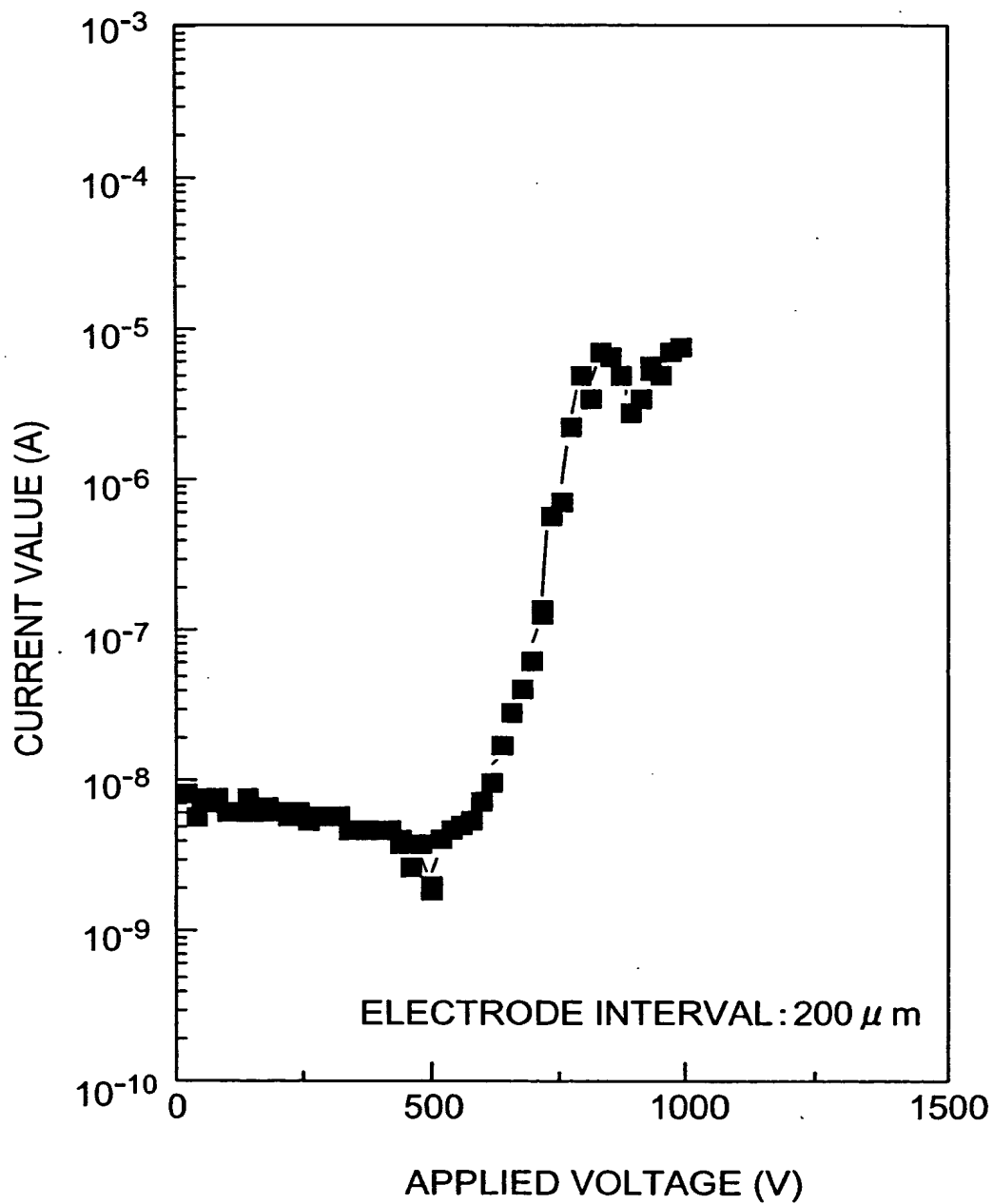
Fig.18



PROTRUSION WHERE AN AL ELECTRODE
IS FORMED EXCEPT FOR THE END PORTION

Fig.19

ELECTRON EMISSION CHARACTERISTIC
OF A SHARP EMITTER INCLUDING
AN AI ION INJECTED LAYER
AND BEING PROVIDED WITH AN AI ELECTRODE

Fig.20

ELECTRON EMISSION CHARACTERISTIC
OF A SHARP EMITTER INCLUDING
A BORON DOPED EXITAXIAL LAYER
AND BEING PROVIDED WITH AN AL ELECTRODE